Form PTO-1449

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LIST OF ART CITED BY APPLICANT

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ATTY. DOCKET NO. M122-1694

SERIAL NO.

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APPLICANT Richard Holscher et al.

FILING DATE GROUP 6/19/01 17-56 U.S. PATENT DOCUMENTS Date Class Subclass Filing Date Document Name *Examiner Number If Appropriate Initial 5,472,829 12/95 KUD Ogawa AA 5,591,566 01/97 ΑB Ogawa 5,641,607 06/97 AC Ogawa et al. AD 5,648,202 07/97 Ogawa et al. 5,677,111 10/97 ΑE Ogawa 5,670,297 09/97 Ogawa et al. AG 5,698,352 12/97 Ogawa et al. ΑH 5,831,321 03/98 Nagayama Αl 5,034,348 07/91 Hartswick et al. ΑJ 6,008,124 12/99 Sekiguchi et al. 08/94 ΑK 5,340,621 Matsumoto et al. M 02/97 ΑL 5,600,165 Tsukamoto et al. FOREIGN PATENT DOCUMENTS Date Class Subclass Translation Country Document Number Yes AM 0-778496 A2/A3 06/97 EPO AN 9-55351 02/97 Japan ΑO ΑP ΑO OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) McKenzie, D. et al. "Now Technology for PACVD", Surface and Coatings Technology 82 (1996), pp. 326-333. Shibata, Noburu, "Plasma Chemical Vapor Deposited Silicon Oxide/Silicon Oxynitride Double Layer Antireflective Coarling for Sulpr Cells", Jap. Journ. of Applied Physics, Vol. 30, No. 5, May 1991, pp. 997-1001. AS AT EXAMINER DATE CONSIDERED 8-5-02

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not

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GROUP 756

				U.S. PATENT DOCUMENTS				
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing If Appro	Date opriate
(W)	AA	5,968,324	10/99	Cheung et al.		·		
	АВ	5,872,385	02/99	Taft et al.				
	. AC	5,883,011	04/99	Lin et al.				
1/	AD	5,960,289	09/99	Tsui et al.				
(UM)	AE	6,020,243	02/00	Wallace et al.				
	AF							
	AG							
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				FOREIGN PATENT DOCUMENTS			-	
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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LIST OF ART CITED BY APPLICANT

APPLICANTS

AJ JP06067019A Japan (Abstract) KOP AK 0 471 185 A2 7 9 1 EPO		_	(Use several sheets			Richard Holscher	et al.			
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Initial Namber					U.S. PATENT DOCUMENTS	i				
AB 5,441,797 08/1593 Hogan et al. AC 5,472,827 120,595 Ogwar et al. AD 5,574,356 1007/87 Nagayama AE 5,710,667 01/2098 Foote et al. AF 5,731,242 03/24/98 Parat et al. AG 5,741,721 04/21/98 Sievens AH 5,759,755 06,602,98 Park et al. AN 5,759,755 06,602,98 Park et al. AN 1,583,652 11/1798 McTeer FOREIGN PATENT DOCUMENTS Document Number Document Number Document Number AN 1,583,652 11/1798 McTeer FOREIGN PATENT DOCUMENTS Country Class Subclass Translation Yes AN 0,471,185,A2 T 9 1 Epo AN 0,588,687 A2 8 9 3 Epo COTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) AN ARTICLE: Beacher, C. et al., "Delectric antireflective coatings for DUV lithography", Solid State Technology (March 1997). Pp. 109-114. AN ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of A2® BARLi" Bottom Coating on Back Conditions", SPH Vol. 3049 (1997), pp. 963-973. AP TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49, December 19 7 6. AN ARTICLE: Dammel, R. R. et al., "Fundamentals of Optics", Properties of Light, pp. 9-16, December 19 7 6.				Date	Name		Class	Subclass		
AC 5.472,827 120595 Ogswa et al. AD 5.674,356 100707 Nagayama — — — — — — — — — — — — — — — — — —	W	AA	4,954,867	09/04/90	Hosaka					
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) AN ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp. 109-114. AO ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi" Bottom Coating on Back Conditions", SPII Vol. 3049 (1997), pp. 963-973. TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49, December 1991. AQ TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10, December 1976. TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441, 1986.	MAD	AL	0 588 087 A2		EPO				ļ	
AN ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp. 109-114. AO ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi™ Bottom Coating on Back Conditions", SPII Vol. 3049 (1997), pp. 963-973. TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49, December 1991. AQ TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10, December 1976. AR TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441, 1986.	KAD	AM		 		- Partiant Page 5	740)	_		L
pp. 109-114. AO ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi™ Bottom Coating on Back Conditions", SPII Vol. 3049 (1997), pp. 963-973. AP TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49, December 1991. AQ TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10, December 1976. AR TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441, 1986.		,,		K KEFEKEN	CES (including Author, Title, Date	e, refunent rages, r				
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Vol. 3049 (1997), pp. 963-973. TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49, December 1991. AQ TEXT: Jenkins, F. et al., "Fundamentals of Optics", Properties of Light, pp. 9-10, December 1976. TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441, 1986.	VVIO		рр. 109-114.		• •				_	
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